

FORM PTO-1449				Atty. Docket No. XA-7431L		Appln. No. 10/759,603	
<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>				Applicant Naomasa Shiraishi et al.			
				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA	3,492,635	1/27/70	Farr	340	15.5	
AM	AB	3,630,598	12/28/71	Little, Jr.	350	157	
AM	AC	3,639,039	2/1/72	Rhodes, Jr.	350	162	
AM	AD	3,658,420	4/25/72	Axelrod	356	71	
AM	AE	3,729,252	4/24/73	Nelson	350	162	
AM	AF	3,770,340	11/6/73	Cronin et al.	350	162	
AM	AG	3,776,633	12/4/73	Frosch et al.	355	132	
AM	AH	4,132,479	1/2/79	Dubroeuq et al.	355	71	
AM	AI	4,207,370	6/10/80	Liu	428	204	
AM	AJ	4,291,938	9/29/81	Wagner	350	91	
AM	AK	4,472,023	9/18/84	Yamamoto	350	162.11	
AM	AL	4,739,373	4/19/88	Nishi et al.	355	53	
AM	AM	4,749,278	6/7/88	van der Werf	356	401	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
AM	AN	0 346 844	12/20/89	EPO			
AM	AO	0 352 975	1/31/90	EPO			
AM	AP	59-83165	5/14/84	JAPAN			abstract
AM	AQ	61-41150	2/27/86	JAPAN			abstract
AM	AR	2-50417	2/20/90	JAPAN			abstract
AM	AS	2-48090	10/24/90	JAPAN			abstract
OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT	"Extended Focal Depth Optical Microlithography", IBM Technical Disclosure Bulletin, Vol. 32, June 1989, pp 125-127.					
AM	AU	Delmer L. Fehrs et al., "Illuminator Modification of an Optical Aligner", <u>KTI Microelectronics Seminar</u> , Nov. 6-7, 1989, pp. 217-230.					
AM	AV	David J. Cronin et al., "Dynamic Coherent Optical System", <u>Optical Engineering</u> , March/April 1973, Vol. 12, pp. 50-55.					
Examiner Alan Mathews				Date Considered 11-23-2004			
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				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA*	4,778,275	10/18/88	van den Brink et al.	356	401	
AM	AB*	4,780,749	10/25/88	Schulman	357	12	
AM	AC*	4,789,222	12/6/88	Ota et al.	350	167	
AM	AD*	4,814,829	3/21/89	Kosugi et al.	355	43	
AM	AE*	4,828,392	5/9/89	Nomura et al.	356	401	
AM	AF*	4,841,341	6/20/89	Ogawa et al.	355	43	
AM	AG*	4,851,882	7/25/89	Takahashi et al.	355	46	
AM	AH*	4,853,756	8/1/89	Matsuki	355	71	
AM	AI*	4,854,669	8/8/89	Birnbach et al.	350	162.12	
AM	AJ*	4,931,830	6/5/90	Suwa et al.	355	71	
AM	AK*	4,947,413	8/7/90	Jewell et al.	378	34	
AM	AL*	4,970,546	11/13/90	Suzuki et al.	355	53	
AM	AM*	4,988,188	1/29/91	Ohta	353	122	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AN						
	AO						
	AP						
	AQ						
	AR						
	AS						
OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT*	Victor Pol et al., "Excimer laser based lithography: a deep-ultraviolet wafer stepper for VLSI processing", <u>Optical Engineering</u> , Vol. 26, April 1987, pp. 311-318.					
AM	AU*	D. H. Barry, "Pattern recognition automatic fine alignment", <u>SPIE</u> , Vol. 334, 1982, pp. 10-16.					
AM	AV*	S. T. Yang et al., "Effect of central obscuration on image formation in projection lithography", <u>SPIE</u> , Vol. 1264, 1990, pp. 477-485.					
Examiner Alan Mathews				Date Considered 11-23-2004			
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10/759,603

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Naomasa SHIRAISHI et al.

Filing Date

HEREWITH

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U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA^	4,992,825	2/12/91	Fukuda et al.	355	53	
AM	AB^	5,004,348	4/2/91	Magome	356	401	
AM	AC^	5,091,744	2/25/92	Omata	355	53	
AM	AD^	5,121,160	6/9/92	Sano et al.	355	53	
AM	AE^	5,153,419	10/6/92	Takahashi	250	201.1	
AM	AF^	5,191,374	3/2/93	Hazama et al.	355	43	
AM	AG^	5,208,629	5/4/93	Matsuo et al.	355	53	
AM	AH^	5,237,367	8/17/93	Kudo	355	67	
AM	AI^	5,245,384	9/14/93	Mori	355	67	
AM	AJ^	5,264,898	11/23/93	Kamon et al.	355	67	
AM	AK^	5,286,963	2/15/94	Torigoe	250	201.2	
AM	AL^	5,309,198	5/3/94	Nakagawa	355	67	
AM	AM^	5,329,336	7/12/94	Hirano et al.	355	53	

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AN^						
	AO^						
	AP^						
	AQ^						
	AR^						

OTHER (including author, title, date, pertinent pages, etc.)

AM	AS^	Naomasa Shiraishi et al., "Optical/Laser Microlithography V", SPIE- The International Society for Optical Engineering, Vol. 1674, March 11-13 1992, pp. 741-752.
AM	AT^	George O. Reynolds, "A Concept for a High Resolution Optical Lithographic System for Producing One-Half Micron Linewidths", SPIE, Vol. 633, 1986, pp. 228-238.
AM	AU^	A. Szegevári, "On the use of an Illumination azimuth diaphragm during coaxial dark field illumination", January 28, 1923, pp. 1-11.

Examiner

Alan Mathews

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U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA#	5,337,097	8/9/94	Suzuki et al.	353	101	
AM	AB#	5,392,094	2/21/95	Kudo	355	67	
AM	AC#	5,440,426	8/8/95	Sandstrom	359	559	
AM	AD#	5,446,587	8/29/95	Kang et al.	359	562	
AM	AE#	5,673,102	9/30/97	Suzuki et al.	355	53	
AM	AF#	Re 34,634	6/7/94	Konno et al.	362	268	
AM	AG#	5,586,170	11/94	Muraki	355	67	
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FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AN						
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OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT#	George Needham, "The Practical Use of The Microscope Including Photomicrography", 1958, pp. 315-327 and 97					
AM	AU#	John Strong, "Concepts of Classical Optics", 1958, pp. 525-536.					
AM	AV#	Akira Imai et al., "Lens aberration measurement technique using attenuated phase-shifting mask", Device Development Center, Hitachi Ltd.					
Examiner Alan Mathews				Date Considered 11-23-2004			
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	AN						
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OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT+	Miyoko Noguchi et al., "Subhalf Micron Lithography System with Phase-Shifting Effect", <u>SPIE</u> , Vol. 1674, 1992, pp. 92-104.					
AM	AU+	N. Nomura et al., "Heterodyne Holographic Nanometer Alignment for a Wafer Stepper", <u>Microelectronic Engineering</u> 11, 1990, pp. 133-136.					
AM	AV+	Emi Tamechika et al., "Investigation of single sideband optical lithography using oblique incidence illumination", J. Vac. Sci. Technol. B, Nov/Dec 1992, pp. 3027-3031.					
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	AN						
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OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT	Keiichiro Tounai et al., "Resolution improvement with annular illumination", VLSI Development Division, NEC Corporation, 1992.					
AM	AU	H. Fukuda et al., "Characterization of Super-Resolution Photolithography", <u>IEEE</u> , 1992, pp. 3.2.1 - 3.2.4.					
AM	AV	Hiroshi Fukuda et al., "A New Pupil Filter for Annular Illumination in Optical Lithography", <u>Jpn. J. Appl. Phys.</u> , Vol. 31, 1992, pp 4126-4130.					
Examiner <i>Alan Mathews</i>				Date Considered <i>11-23-2004</i>			
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	AN						
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OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT♦	Maksymilian Pluta, "Principles and Basic Properties" <u>Advanced Light Microscopy</u> , Vol. 1, 1988, pp. 460-463.					
AM	AU♦	H. Wolfgang Zieler, "Physical Optical Aspects of Image Formation", <u>The Optical Performance of the Light Microscope</u> , 1974, pp. 32-55.					
	AV♦						
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	AL						
	AM						
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OTHER (including author, title, date, pertinent pages, etc.)							
AM	AR*	James R. Sheats et al., "Optical Lithography Modeling", <u>Microlithography Science and Technology</u> , Chapters 2-4, 1998, pp. 109-271.					
AM	AS*	Joseph W. Goodman, "Frequency Analysis of Optical Imaging Systems", <u>Introduction to Fourier Optics</u> , Chapter 6, 1968, pp. 101-197.					
AM	AT*	Maksymilian Pluta, "Specialized Methods", <u>Advanced Light Microscopy</u> , Vol. 2, 1989, pp. 100-113.					
Examiner <i>Alan Mathews</i>				Date Considered <i>11-23-2004</i>			
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	AA						
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	AN						
	AO						
	AP						
	AQ						
	AR						
	AS						
OTHER (including author, title, date, pertinent pages, etc.)							
AM	AT◇	Satoru Asai, et al., "Improving projection lithography image illumination by using sources far from the optical axis", <u>J. Vac. Sci. Technol.</u> , Vol. 9, Nov/Dec 1991, pp. 2788-2791.					
AM	AU◇	B. J. Lin, "Optical Methods for Fine Line Lithography", <u>Fine Line Lithography</u> , Chapter 2, 1980, pp. 107-232.					
	AV◇						
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U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA	4,497,015	1/85	Konno et al.	362	268	
AM	AB	4,952,815	8/90	Nishi	250	548	
AM	AC	5,307,207	4/94	Ichihara	367	259	
AM	AD	5,098,184	3/92	vanden Brandt et al.	353	38	
AM	AE	4,851,978	7/89	Ichihara	355	67	
AM	AF	5,153,773	10/92	Muraki et al.	362	268	
AM	AG	4,497,013	1/85	Ohta	362	268	
AM	AH	4,939,630	7/90	Kikuchi et al.	362	268	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
AM	AL	62-50811	10/87	JAPAN			partial
AM	AM	WO 92/03842	3/92	WIPO (abstract)			
AM	AN	61-91662	5/9/86	Japan			yes
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AM	AA	4,918,583	4/90	Kudo et al.	362	268	
AM	AB	5,300,971	4/5/94	Kudo	355	67	
AM	AC	6,252,647	6/26/01	Shiraishi	355	53	
AM	AD	6,211,944	4/3/01	Shiraishi	355	53	
AM	AE	4,619,508	10/28/86	Shibuya et al.	355	67	
AM	AF	4,769,750	9/6/88	Matsumoto et al.	362	268	
AM	AG	4,974,919	12/4/90	Muraki et al.	362	268	
AM	AH	5,016,149	5/14/91	Tanaka	362	268	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
AM	AL	WO 88/08932	11/17/88	WIPO			
AM	AM	1,137,243	12/18/68	United Kingdom			
	AN						
	AO						
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OTHER (including author, title, date, pertinent pages, etc.)							
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AM	AA	5,638,211	6/10/97	Shiraishi	359	559	
AM	AB	4,637,691	1/87	Uehara et al.	359	727	
AM	AC	4,498,742	2/85	Uehara	359	727	
AM	AD	4,370,026	1/83	Dubroeucq et al.	355	71	
AM	AE	4,249,793	2/81	Uehara	359	727	
AM	AF	4,370,034	1/83	Nohda	351	206	
AM	AG	4,780,747	10/88	Suzuki et al.	355	68	
AM	AH	4,668,077	5/87	Tanaka	355	53	
	AI						
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FOREIGN PATENT DOCUMENTS							
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	AL						
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<i>AM</i>	AA	4,566,765	01/28/86	Miyauchi et al.	350	619	
<i>AM</i>	AB	4,476,519	10/09/84	Hayamizu	362	32	
<i>AM</i>	AC	4,275,288	06/23/81	Makosch et al.	219	121	
<i>AM</i>	AD	5,463,497	10/31/95	Muraki et al.	359	618	
<i>AM</i>	AE	4,241,389	12/23/80	Heimer	362	297	
<i>AM</i>	AF	4,547,037	10/15/85	Case	350	3.75	
<i>AM</i>	AG	4,389,701	01/21/83	Phillips	362	308	
<i>AM</i>	AH	4,585,315	04/29/86	Sincerbox et al.	350	525	
<i>AM</i>	AI	5,048,926	9/17/91	Tanimoto	359	487	
	AJ						
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FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
<i>AM</i>	AL	1-295215	11/28/89	Japan			Abstract
<i>AM</i>	AM	56-12615	02/07/81	Japan			Abstract
<i>AM</i>	AN	58-16214	01/29/83	Japan			Abstract
<i>AM</i>	AO	59-49514	03/22/84	Japan			Abstract
<i>AM</i>	AP	0 282 593	09/21/88	Europe			
	AQ						
OTHER (including author, title, date, pertinent pages, etc.)							
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Group

HEREWITH

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA	4,179,708	12/18/79	Sheng et al.	358	128	
	AB						
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Naomasa Shiraishi

Filing Date

January 20, 2004

Group

2851

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA	4,936,665	6/26/90	Whitney	350	451	
AM	AB	5,305,054	4/19/94	Suzuki et al.	355	53	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AN						
	AO						
	AP						
	AQ						
	AR						
	AS						

OTHER (including author, title, date, pertinent pages, etc.)

	AT	
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Examiner

Alan Mathew,

Date Considered

11-23-2004

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

FORM PTO-1449

Atty. Docket No.

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LIST OF DOCUMENTS CITED BY APPLICANT

XA-7431L

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U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
AM	AA	6,233,041	5/15/01	Shiraishi	355	53	
AM	AB	6,636,293	10/21/03	Shiraishi	355	53	
AM	AC	6,665,050	12/16/03	Shiraishi	355	53	
AM	AD	6,704,092	3/9/04	Shiraishi	355	53	
AM	AE	5,719,704	2/17/98	Shiraishi et al.	359	558	
AM	AF	6,100,961	8/8/00	Shiraishi et al.	355	67	
AM	AG	6,377,336	4/23/02	Shiraishi et al.	355	67	
AM	AH	6,392,740	5/21/02	Shiraishi et al.	355	53	
AM	AI	6,710,854	3/23/04	Shiraishi et al.	355	67	
AM	AJ	6,710,855	3/23/04	Shiraishi	355	67	
	AK						
	AL						
	AM						

FOREIGN PATENT DOCUMENTS

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	AN						
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